Oxidation Resistant Coatings Via Combustion Chemical Vapor Deposition (CCVD) Process

MCT

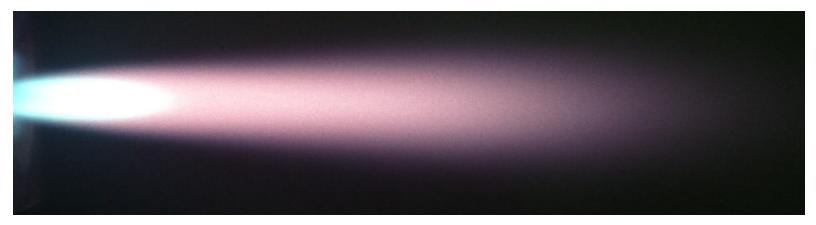
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Presented at EBC Workshop, Nashville, TN

Outline

- Introduction to MCT
- The CCVD technology
- Oxidation resistant coatings development
- Representative examples
- Summary



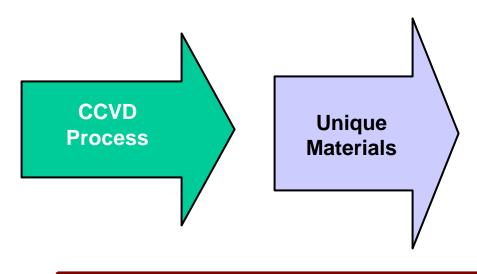
Company History

- Founded in 1994 to advance CCVD process to commercialization
- Graduate member of Georgia Tech's Advanced Technology Development Center
- Grew from government & customer R&D funding -"Bootstrap model"
- Equity investments started in mid-1999
- 37 patents issued and over 150 patents pending worldwide

A Unique Flame Based Technology

- Combustion Chemical Vapor Deposition-CCVD
 - patented
 - open-atmosphere
 - flame-based technique
 - thin films of advanced materials







Target Markets

Target Products

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RF Wireless

- Components for cellular phones
- Components for wireless devices

Nano

- Novel nanopowders
- Catalysts and fuel cell layers
- Fuel injector

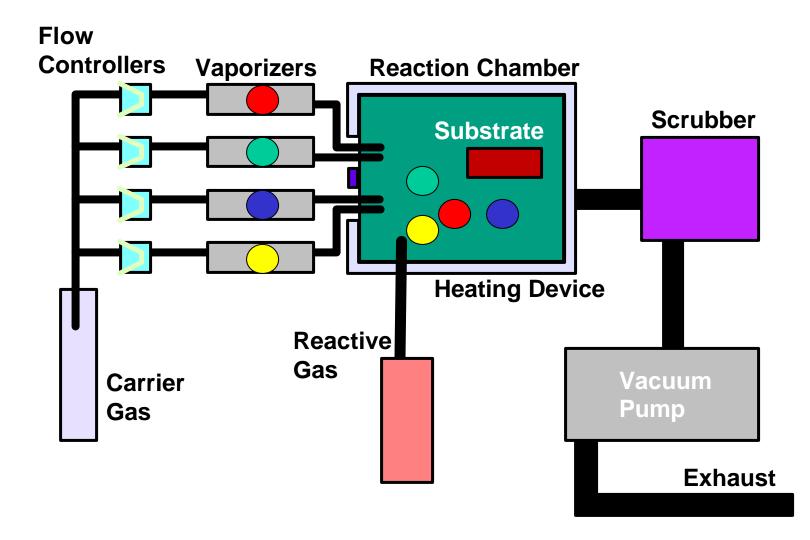
Barriers

- Food and beverage packaging
- Superconducting tapes
- Gas / Moisture / Anti-corrosion

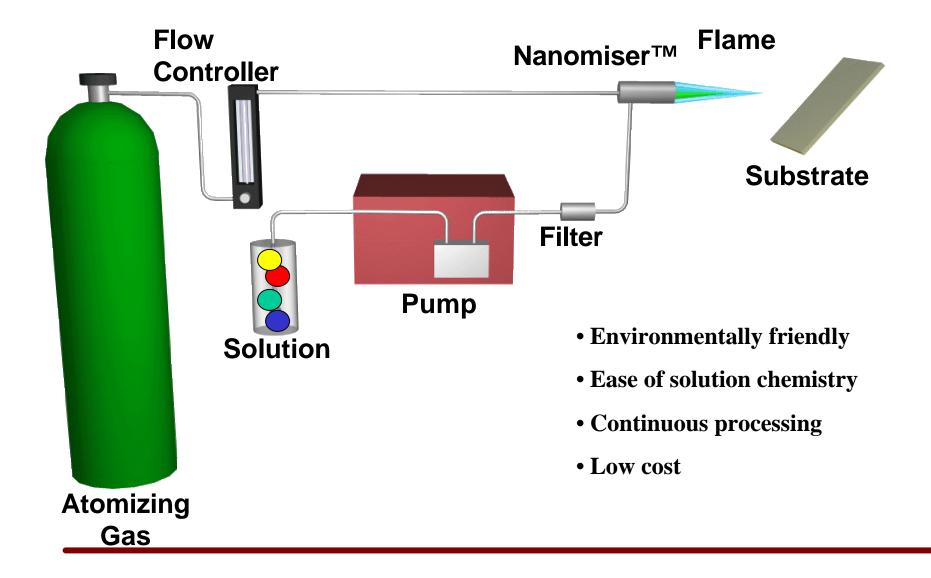
Electronics and Optics

- Next generation circuit boards
- Photonic devices and sensors
- Light emitters and detectors
- Advanced dielectrics
- Solar cell transparent conductive oxides

Traditional CVD System



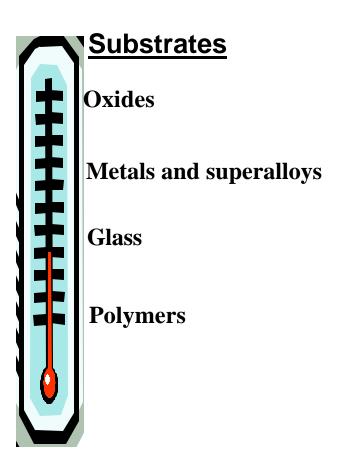
Open Atmosphere CCVD Process



Examples of Deposited Materials

Coatings

- Oxides
 - Simple (silica, alumina)
 - Complex (PZT, YBCO)
 - Multilayers
- Metals
 - Au, Pt
- Polymer composites
- Over 90 Different Materials



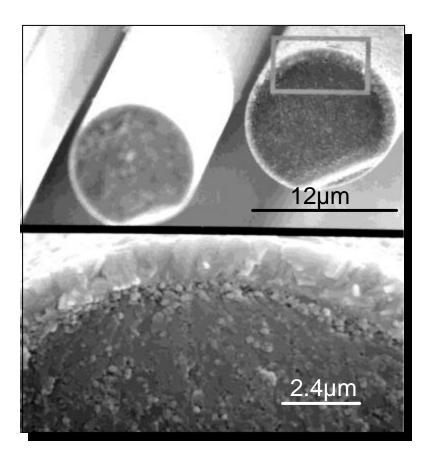
CCVD Technical Advantages: Top Ten List

- Deposits very thin films, 10 nm to thick films > 60 μm
- Controls density/porosity
- Enables high compositional control and multi-layering
- Deposits onto complex/large substrates
 - Not line of sight
- Allows substrate temperatures less than 100°C

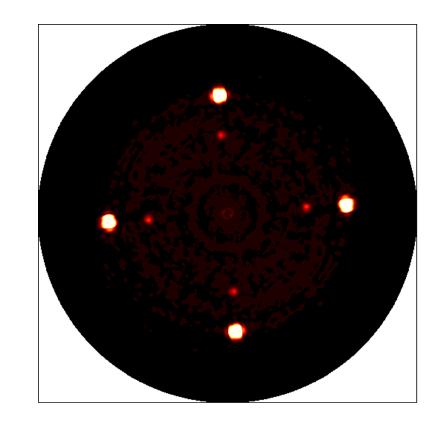
- Offers *in situ* capability
- Forms epitaxial and preferred growth films

- Avoids use of high vapor pressure precursors
- Enables up to 1 µm/minute dense oxide coatings
- Facilitates quick development cycles

Dense and Oriented Coatings Grown via CCVD



 $LaPO_4$ Coatings on a Nextel Fiber Tow



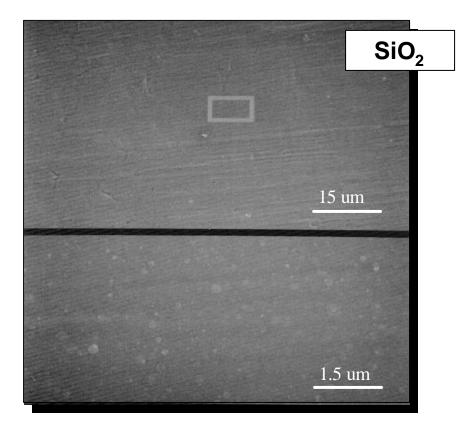
CCVD Yb_2O_3 on CCVD Y_2O_3 on (100) LaAlO₃ (222)

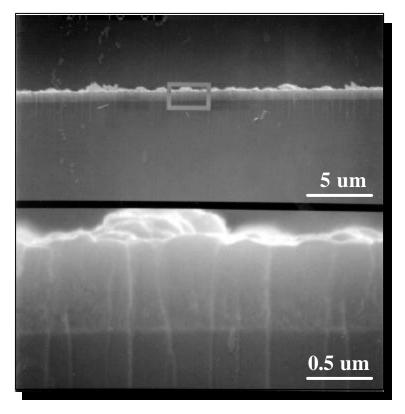
Oxide Coatings Development

- Carbon steel
 - Silica, alumina, chromia and multilayers (< 0.7 microns)

- Static oxidation at 500° C
- Titanium alloy (6AI-4V-Ti)
 - Silica, chromia and multilayers (< 0.7 microns)
 - Static oxidation at 540° C

Dense Silica and Chromia Coatings were Grown



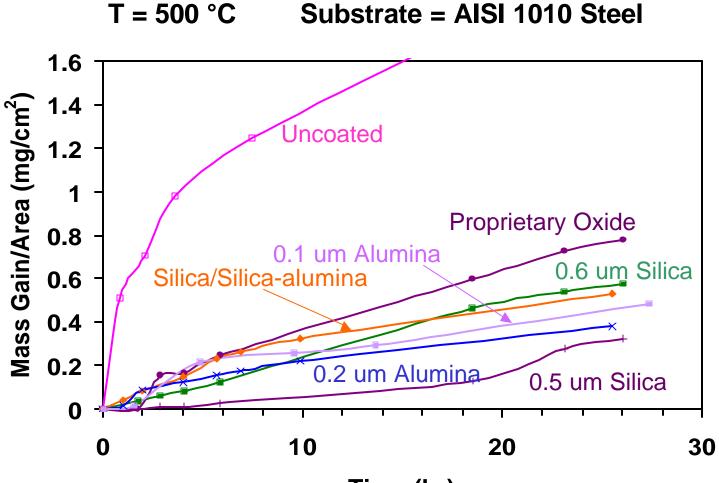


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Cross-section of CCVD Cr_2O_3 on fused silica

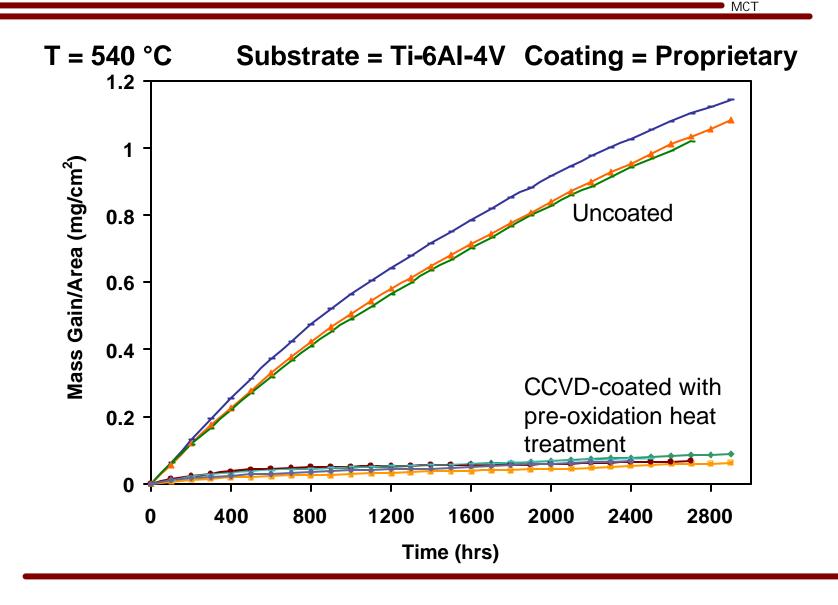
CCVD Oxides Reduce Oxidation Rate of Carbon Steel

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Time (hr)

CCVD Oxides Perform Well in Testing

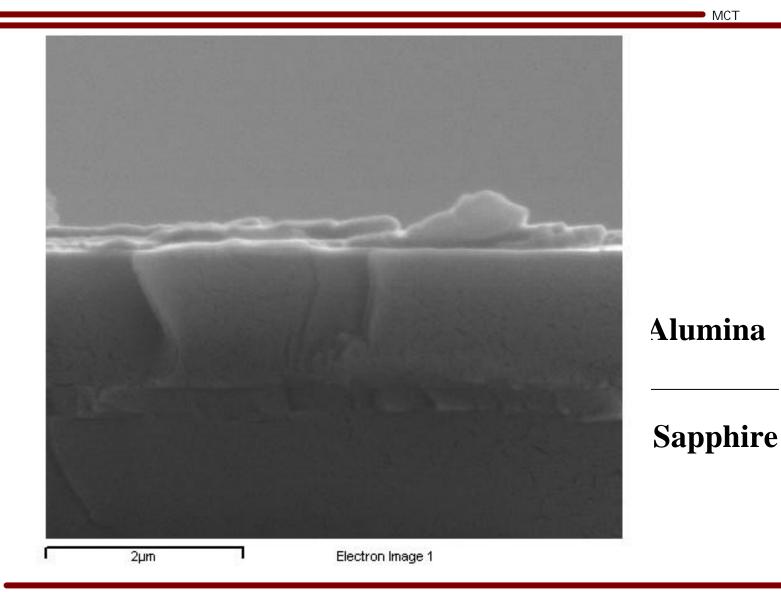


Coatings for Superalloys and TBCs

- Alumina, yttria and proprietary multilayer coatings
- Coatings grown on sapphire and YSZ substrates
 Oxidation at 1100° C up to 300 h to evaluate stability
- Coatings subsequently deposited on TBCs and currently undergoing testing

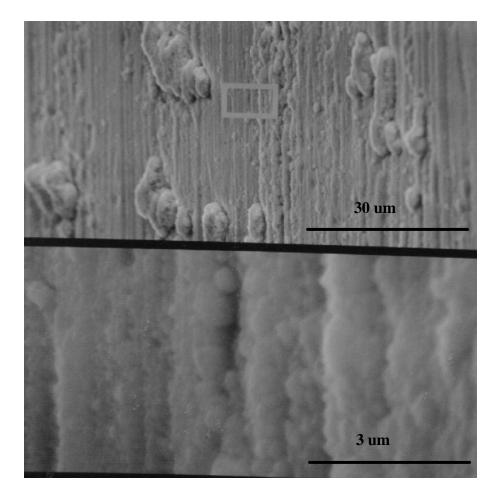
Amorphous Alumina Coatings were Grown

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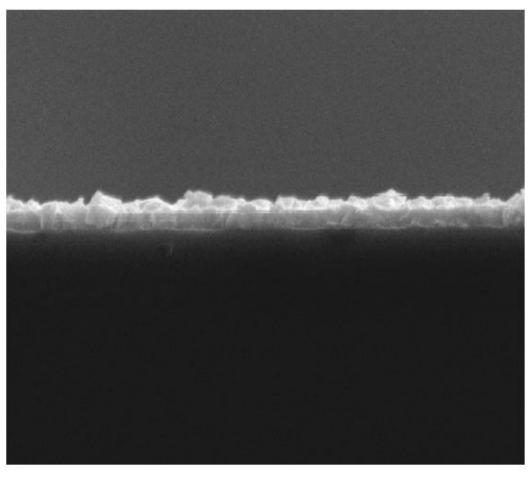


Dense Alumina on a Superalloy Substrate

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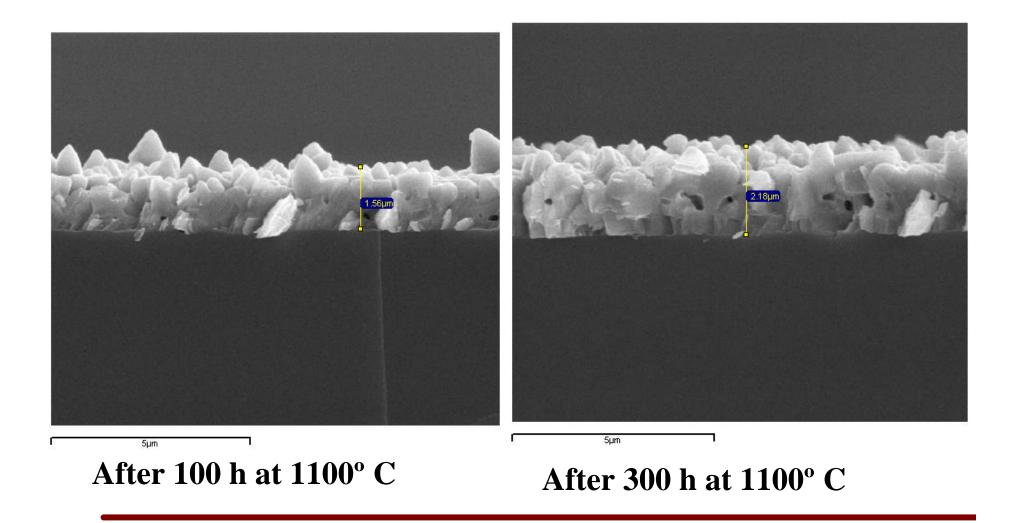


Dense Yttria Coatings were Deposited



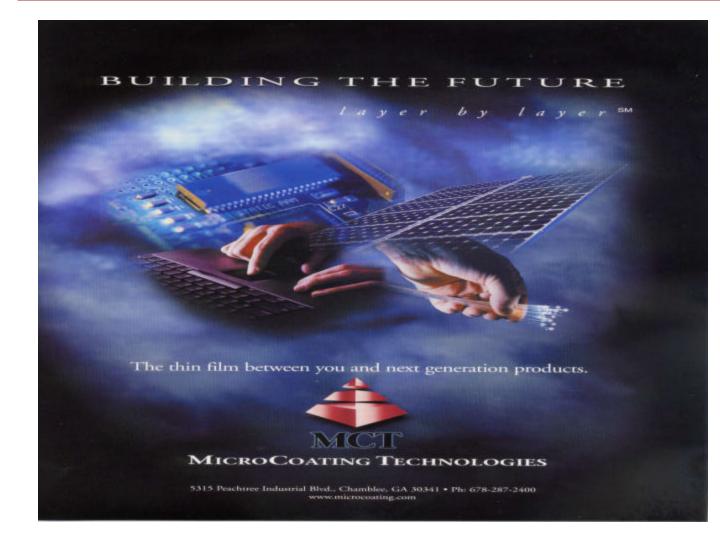
2µm

Dense Multilayer Coatings were Grown and Tested



- CCVD process is well suited for producing oxides, noble metals and composites
- Silica, chromia, alumina, yttria and multilayer coatings were successfully grown via CCVD
- CCVD oxide coatings decrease oxidation rate of carbon steel and titanium alloy by 50 to 90 %
- CCVD oxide coatings are currently being tested for their effectiveness on TBCs

Acknowledgments



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- Neville Richards
- Seth Sundell
- Melanie Gast

Benefits of CCVD



Friendly

- Non-Toxic Precursors
- **Environmentally** Simple Organic Solvents

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• Benign By-products (typically H_2O and CO_2)



Production Flexibility

- Rapid Changeovers
- Short R&D Cycle •



Low-cost

- Capital Costs
- **Precursor Costs**